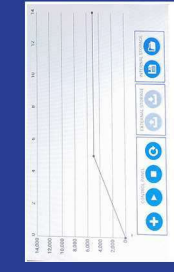


SPECIFICATIONS

DIMENSION (LxBxH)	225 X 235 X 270 (mm)
WEIGHT	10.3 Kgs
CHAMBER SIZE	150 (mm) diameter
POWER INPUT	115/230 VAC, 50 Hz
HOUSING MATERIAL	SS Sheet Metal

225 X 235 X 270 (mm)
10.3 Kgs
150 (mm) diameter
115/230 VAC, 50 Hz
SS Sheet Metal

SYSTEM AND INTERFACE

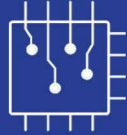


Programmable upto 10 steps
Real time program feedback (RPM, Time)
User friendly interface

Multiple Processors to ensure perfect instruction flow

Nitrogen Purge Facility in the process chamber

STORAGE



USB port facility
Stores data internally or externally



CALIBRATION AND SAFETY



Spirit Level to check planarity
Teflon coated working chamber for inertness
Leak Proof sealing

NIT 12000 V1



CHARACTERISTICS	RANGE/VALUE	TOLERANCE
SPEED	100-12000 RPM	+ 50 RPM
ACCELERATION*	8000 RPM/S	-
MIN INCREMENT	1 RPM	-
DWELL TIME	0-1000 seconds	+ 0.05 s

* Size and weight of the substrate will affect acceleration values

HIGHLY DAMPED VIBRATIONS!
Operational vibrations don't pass on to the chuck thus ensuring stability and uniformity of the coating even on nano-scale

QUICK RESPONSE!
Multiple processors keep the data input and computing independent so as to provide maximum computational ability and quick response

Vacuum Less Chuck!
Accommodates standard substrate sizes
- Cover slip, Microscopic glass slide
2 inch silicon wafers

CUSTOMIZED!
Accommodates customized shapes and sizes

Vacuum Chuck
Customized according to the requirements

Push fit chucks for easy replacement

* The dimensions of the customized substrate should be within .105mm diameter

FEATURES